

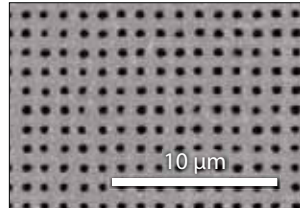
EXAMPLES OF INDUSTRIAL APPLICATIONS

STEEL FOIL M-DRILLING

- No melting
- Micron diameter

Applications:

- Filters
- Functional surfaces

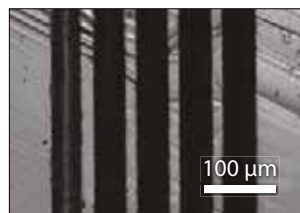


DIAMOND CUTTING

- Low carbonization
- No HAZ
- Low material loss

Applications:

- Diamond sheet cutting
- Chip breaker formation
- Diamond texturing/patterning

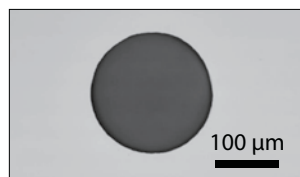


GLASS HOLES

- Various hole sizes with routine taper angle better than 5 deg
- Minimal debris around the edges of holes

Application:

- Microfluidics
- VIAs



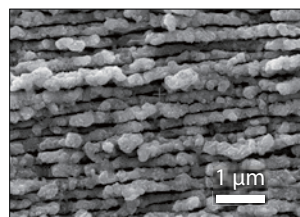
Top view



Cross-section

NANO RIPPLES

- Up to 200 nm ripple period fabricated using ultra-short laser pulses
- Individual nano-feature size on ripples: 10 – 50 nm
- Controlled period, duty cycle and aspect ratio of the ripples



Developed in cooperation with Swinburne University, Australia

Application:

- Detection of materials with increased sensitivity using surface-enhanced Raman scattering (SERS)
- Bio-sensing, water contamination monitoring, explosive detection etc.

METAL MICROMACHINING

- 3D structures formed on steel surface
- High precision and surface smoothness achieved



MARKING OF CONTACT LENS

- Marking made inside the bulk of contact lens, preserving surface of lens and distortions
- Exact positioning of markings – 3D text format



Application:

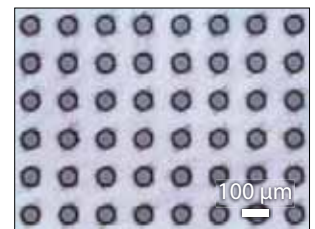
- Product counterfeit protection
- Serial number and customer identification

THIN GLASS DRILLING

- Taper angle control
- Low heat affect
- No cracking or chipping around holes

Applications:

- VIAs

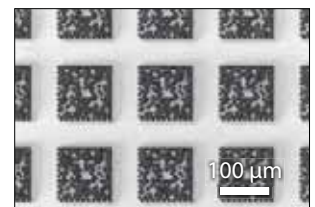


DATAMATRIX

- Data inscribed on a glass surface or inside bulk
- Extremely small elements, down to 5 μm in size

Application:

- Product marking



GLASS TUBE DRILLING

- Controlled damage and depth
- Hole diameter of few microns

Applications:

- Medical applications
- Biopsy equipment

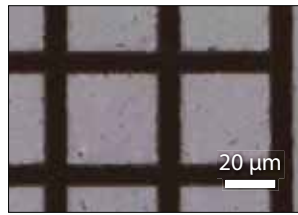


FERROELECTRIC CERAMICS ETCHING

- No or low melting and HAZ
- Easily removable debris
- Good structuring quality

Applications:

- Infrared sensors for cameras
- Memory chips

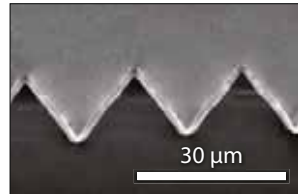


SILICON LASER ASSISTED ETCHING

- No HAZ
- No melting

Applications:

- Solar cell production
- Semiconductor industry

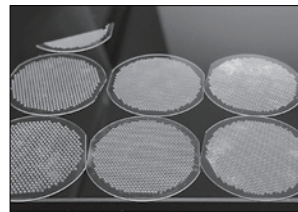


MASK FOR BEAM SPLITTER PATTERN DEPOSITION

- Borosilicate glass
- 150 μm thickness
- ~900 holes per mask
- Mask diameter 25.4 mm

Application:

- Selective coating

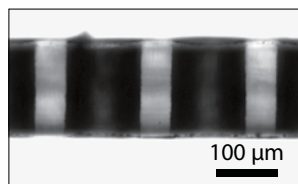
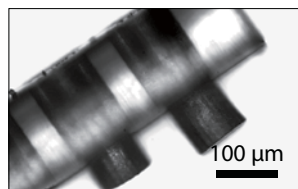


STENT CUTTING

- Holes in stent wall, cross-section view
- Polymer stent
- No heat effect, no debris
- Minimal taper effect

Application:

- Vascular surgery

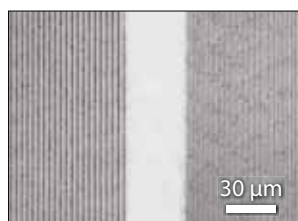


TEXTURIZED SAPPHIRE SURFACE

- Micron resolution
- Large area processing
- Single pulses used to form craters on the surface

Application:

- Better light extraction in LED
- Semiconductor structure growth



MARKING AND PATTERNING

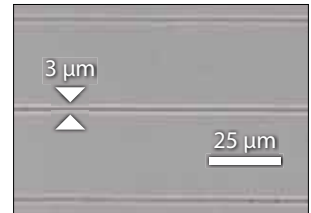
- Smallest spots down to 3 μm in width
- Micron level positioning
- No heat effect



Metal

MICRO CHANNEL FORMATION

- Wide range of materials – from fused silica to polymers
- Controllable channel shape
- Low debris
- Smooth surface



Applications:

- Microfluidic sensors
- Waveguides



OPTICAL FIBER DRILLED TO THE CORE

- Diameter from <math><10 \mu\text{m}</math>
- Various hole profiles possible
- Depth and angle control

Applications:

- Optical fiber sensors
- Material science

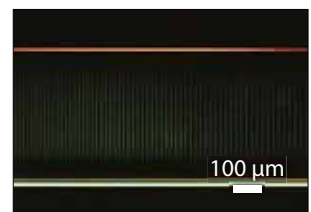


OPTICAL FIBER SCATTERING

- No impact on fiber strength
- No surface damage
- Even light dispersion

Applications:

- Medical fibers
- Oncology



SYNTHETIC RUBY DRILLING

- No cracks after drilling
- Taper angle control

Application:

- High precision mechanical parts



GLASS BULK PROCESSING

- Refractive index volume modification
- Bragg gratings with 99% diffraction efficiency
- Birefringent gratings/elements
- Low influence on strength of the substrate



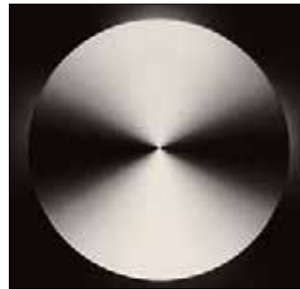
Birefringence modification inside fused silica. Photo in crossed polarized light



Sapphire



Glass

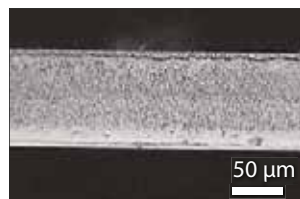


S-waveplate *

* M. Beresna, M. Gecevičius, P.G. Kazansky and T. Gertus, Radially polarized optical vortex nanostructuring of glass, Appl. Phys. Lett. 98, 201101 (2011).

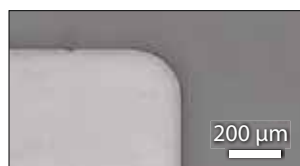
NON TEMPERED GLASS CUTTING

- Thickness: 0.03 – 0.3 mm
- Mechanical or heat assisted break after scribing
- Speed: up to 800 mm/s
- Any shape
- Round corners
- Surface quality: Ra ≤ 2 μm



SAPPHIRE CUTTING

- Thickness: 100 – 900 μm
- Easy to break
- Circle shapes diameter: 3 – 15 mm
- Corner radius: from 0.5 mm
- Speed: up to 800 mm/s
- Cut quality: Ra ≤ 2 μm
- No surface cracks
- No or low chipping
- Non ablating process



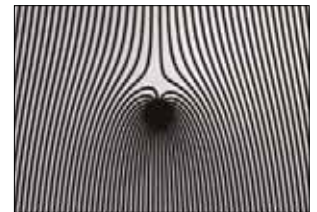
Thickness: 420 μm, clear sapphire

SELECTIVE METAL COATING ABLATION (REMOVAL)

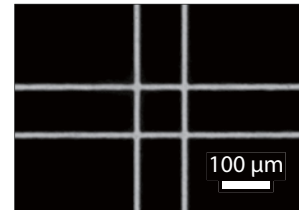
- Selective ablation of metal coatings from various surfaces
- Depth and geometry of ablation may vary

Application:

- Lithography mask production
- Beam shaping elements
- Optical apertures
- Other



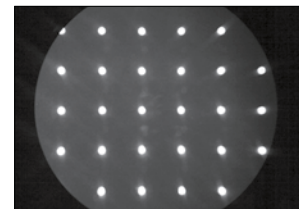
Amplitude grating formation



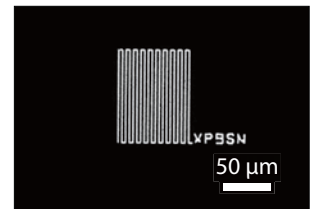
Titan coating selective ablation



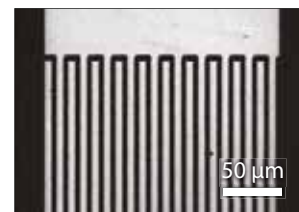
Chrome ablation for beam shaping



Aperture array fabrication



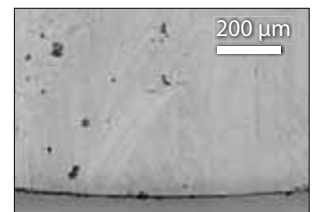
Gold layer removal without damage to MgO substrate – Au layer removal without damaging



Chrome ablation from glass substrate

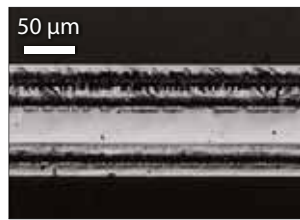
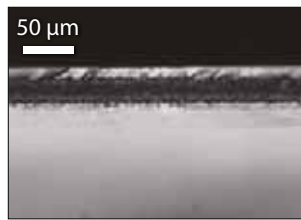
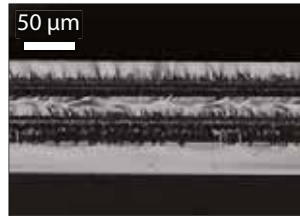
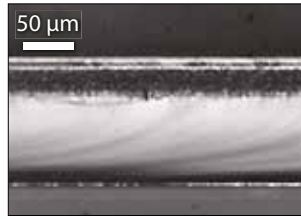
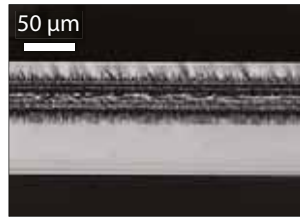
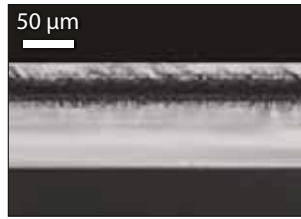
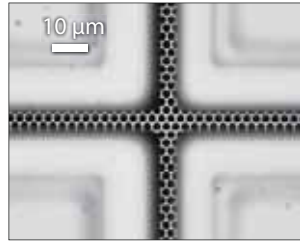
TEMPERED GLASS CUTTING

- Single pass process
- In bulk damage (closed cut), surface remains intact, practically no debris
- Homogeneous cut surface



SAPPHIRE DICING FOR LED INDUSTRY

- Wafer thickness 50 to 330 μm
- Narrow street width up to ~10 μm
- Bending strength (650–900 MPa)
- High light extraction efficiency
- Controllable damage length
- Easy breaking
- Scribing with DBR coated backside of sapphire

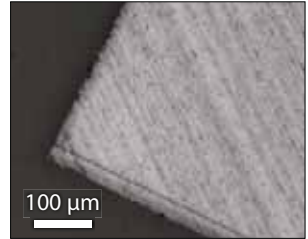
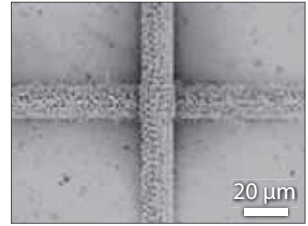


SILICON CARBIDE DICING

- No chipping on the edges
- Cleaved-surface roughness <1 μm
- Easy breaking

Applications:

- High power, high frequency electronics



Samples provided by
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www.evanaotech.com

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